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Substitute for Form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <small>(use as many sheets as necessary)</small>				<i>Complete if Known</i>	
				Application Number	Based on 09/356,376 1-1724, 126
				Filing Date	July 19, 1999 12/11/03
				First Named Inventor	Hongyong ZHANG et al.
				Group Art Unit	2871 176
				Examiner's Name	Kenneth Parker D
Sheet	1	of	3	Attorney Docket Number	0756-7224

U.S. PATENT DOCUMENTS

Examiner Initials ¹	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
DV		5,849,043		Zhang et al.	12/15/98	
		4,177,372		Kotera et al.	12/04/79	
		4,370,175		Levatter	01/25/83	
		4,436,557		Wood et al.	03/13/84	
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		5,205,036		Yamazaki	04/27/93	
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DQ		5,346,850		Kaschmitter et al.	09/13/94	

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		Office ³	Number ⁴	Kind Code ² (if known)				
DV		JP	58-103140			06/20/83		Abst.
		JP	55-150238			11/22/80		Abst.
		JP	56-30721			03/27/81		Abst.
DQ		JP	62-142370			06/25/87		Abst.

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DQ		X. Tong, et al., "Effect of Si-Substrate Heating During Laser-Induced B-Doping," Appl. Phys. A Vol. 59 (March 1994) pp. 189-191.	

Examiner Signature	DV	Date Considered	10/3/05
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¹ Unique citation designation number. ² See attached Kinds of U.S. Patent Documents. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

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Sheet	2	of	3	Application Number	Based on 09/356,176 TO 724,126
				Filing Date	July 19, 1998 12/1/03
				First Named Inventor	Hongyong ZHANG et al.
				Group Art Unit	2874 1765
				Examiner Name	Kenneth Parker DPO
				Attorney Docket Number	0756-7224

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		Number	Kind Code ² (if known)		
JP	5,566,009			Yamazaki et al.	10/15/96
	5,583,369			Yamazaki et al.	12/10/96
	5,946,561			Yamazaki et al.	08/31/99
	5,938,839			Zhang	08/17/99
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JP	01-259530				10/17/89
	JP 50-117374				09/13/75
	JP 62-130562				06/12/87
	JP 64-011323				01/13/89
	JP 02-222545				09/05/90
	JP 02-224339				09/06/90
	JP 02-226732				09/10/90
	JP 01-156725				06/20/89
JP	57-162339				10/06/82

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JP		A Slaoui, et al., "Boron Doping of Silicon by Excimer Laser Irradiation," J. Appl. Phys. A 50 (1990) pp. 479-484.			
		Kawachi et al., "Large Area Doping Process for Fabrication of Poly-Si Thin Film Transistor Using Bucket Ion Source and XeCl Excimer Laser Annealing," December 1990, pp. L2370-2372, Jpn. J. Appl. Phys. 29(12) L2370.			
JP		Sameshima et al., "XeCl Excimer Laser Annealing Used to Fabricate Poly-Si TFT's," October 1989, pp. 1789-1793, Japanese J. of Appl. Phys., Vol. 28, No. 10.			

Examiner Signature	JP	Date Considered	10/30/05
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20		5,521,107		Yamazaki et al.	05/28/96	
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		6,331,723	B1	Yamazaki et al.	12/18/01	
		6,195,139		Yamazaki et al.	02/27/01	
		4,859,908		Yoshida et al.	08/22/89	
		4,734,550		Imamura et al.	03/29/88	
		5,372,836		Imahashi et al.	12/13/94	
		5,861,337		Zhang et al.	01/19/99	
20		6,261,856		Shinohara et al.	07/17/01	

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Examiner Initials	Cite No. ¹	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ³
		Office ⁴	Number ⁴ (if known)				
20		JP	54-131866		10/13/79		Abst.
		JP	01-101625		04/19/89		Abst.
20		JP	02-222154		09/04/90		Full

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ³
20		Semiconductor World, "Excimer Laser Annealing Apparatus," pp. 196-197, October 1, 1992, (with full English translation)	

Examiner Signature	Ed	Date Considered	10/3/05
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